



Application : 10/731,187 Docket: A305  
Filing Date : 12/09/2003  
Inventor : Sivarama K. Kuchibhotla et al.  
Title : **ILLUMINATION COMPENSATOR FOR CURVED  
SURFACE LITHOGRAPHY**  
  
Date : Friday, October 14, 2005

**SECTION A –Amendments to the claims:**

Claim 1. (currently amended) :

A projection lithography system, for curved surface lithography, having a number of required transmissive elements in a light path controlled by projection optics and illumination optics

characterized in that:

the illumination optics has means to form an illumination compensator 'Zerogen' having the zero-power aggregate optical effect of two closely-spaced identical meniscus elements back-to-back.